L Number	Hits	Search Text	DB	Time stamp
1	37	monitor\$4 near5 wafer near5 temperature	USPAT	2002/11/29 10:13
		same reactor		
3	1	(monitor\$4 or measur\$4) and 6,214,116	USPAT	2002/11/29 10:21
5	1	(si or silicon) and 6,214,116	USPAT	2002/11/29 10:22
8	32	strip adj heater near5 coils	USPAT	2002/11/29 10:35
9	33	(silicon cr si) and rotat\$4 near5 wafer\$1	USPAT	2002 11 29 10:41
		and preheat\$4 near2 gas		
-	1	isotherm\$4 and rotat\$4 near5 wafer\$1 and	USPAT	2002 11/19 10:11
		preheat\$4 near2 gas and velocity adj		
		gradient		
_	1	isotherm\$4 and rotat\$4 near5 wafer\$1 and	USPAT	2002/11/27 14:02
		preheat\$4 near2 gas		
-	37	rotat\$4 near5 wafer\$1 and preheat\$4 near2	USPAT	2002/11,29 10:40
		gas		